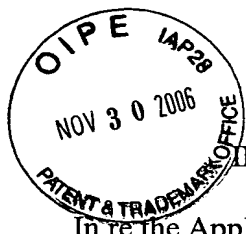


IFW

PATENT APPLICATION



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Takao SAITO et al.

Group Art Unit: 1762

Application No.: 10/766,806

Examiner: B. CHEN

Filed: January 30, 2004

Docket No.: 115556

For: METHODS FOR PRODUCING THIN FILMS ON SUBSTRATES BY PLASMA CVD
(AS AMENDED)

AMENDMENT UNDER 37 C.F.R. §1.111

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In reply to the August 30, 2006, Office Action, please consider the following:

Amendments to the Claims as reflected in the listing of claims; and

Remarks.